

VL5091 MEMS AND NEMS

DETAILED SYLLABUS

OBJECTIVES:

- To introduce the concepts of microelectromechanical devices.
- To know the fabrication process of Microsystems.
- To know the design concepts of micro sensors and micro actuators.
- To familiarize concepts of quantum mechanics and nano systems.

UNIT I OVERVIEW

New trends in Engineering and Science: Micro and Nanoscale systems, Introduction to Design of MEMS and NEMS, MEMS and NEMS – Applications, Devices and structures. Materials for MEMS: Silicon, silicon compounds, polymers, metals.

UNIT II MEMS FABRICATION TECHNOLOGIES

Microsystem fabrication processes: Photolithography, Ion Implantation, Diffusion, Oxidation. Thin film depositions: LPCVD, Sputtering, Evaporation, Electroplating; Etching techniques: Dry and wet etching, electrochemical etching; Micromachining: Bulk Micromachining, Surface Micromachining, High Aspect- Ratio (LIGA and LIGA-like) Technology; Packaging: Microsystems packaging, Essential packaging technologies, Selection of packaging materials.

UNIT III MICRO SENSORS

MEMS Sensors: Design of Acoustic wave sensors, resonant sensor, Vibratory gyroscope, Capacitive and Piezo Resistive Pressure sensors- engineering mechanics behind these Microsensors. Case study: Piezo-resistive pressure sensor.

UNIT IV MICRO ACTUATORS

Design of Actuators: Actuation using thermal forces, Actuation using shape memory Alloys, Actuation using piezoelectric crystals, Actuation using Electrostatic forces (Parallel plate, Torsion bar, Comb drive actuators), Micromechanical Motors and pumps. Case study: Comb drive actuators.

UNIT V NANOSYSTEMS AND QUANTUM MECHANICS

Atomic Structures and Quantum Mechanics, Molecular and Nanostructure Dynamics: Schrodinger Equation and Wave function Theory, Density Functional Theory, Nanostructures and Molecular Dynamics, Electromagnetic Fields and their quantization, Molecular Wires and Molecular Circuits.

REFERENCES:

1. Chang Liu, "Foundations of MEMS", Pearson education India limited, 2006.
2. Marc Madou, "Fundamentals of Microfabrication", CRC press 1997
3. Stephen D. Senturia, "Micro system Design", Kluwer Academic Publishers, 2001
4. Sergey Edward Lyshevski, "MEMS and NEMS: Systems, Devices, and Structures" CRC Press, 2002.